

電場下力-位移之關係圖 70 圖5.15 相同電壓下力-位移之關係圖 70 圖5.16 不同厚度下電場-力之關係圖 71 圖5.17 不同厚度下電壓-力之關係圖 71 圖5.18-A 40V作動位移圖 73 圖5.18-B 40V-3D作動位移圖 73 圖5.19-A 20V荷重計下位移變形圖 74 圖5.19-B 20V-3D作動位移圖 74 圖5.20-A 40V荷重計下位移變形圖 75 圖5.20-B 40V-3D作動位移圖 75 圖5.21-A 60V荷重計下位移變形圖 76 圖5.21-B 60V-3D作動位移圖 76 圖5.22-A 80V荷重計下位移變形圖 77 圖5.22-B 80V-3D作動位移圖 77 圖5.23-A 100V荷重計下位移變形圖 78 圖5.23-B 100V-3D作動位移圖 78 圖5.24-A積層40V作動位移圖 79 圖5.24-B積層40V-3D作動位移圖 79 圖5.25-A積層40V荷重計下位移變形圖 80 圖5.25-B積層40V-3D作動位移圖 80 圖5.26 微液滴觀測系統 82 圖5.27 噴墨驅動波形之設計 83 圖5.28 微液滴噴墨之現象 83 圖5.29 微液滴無法噴出之現象 83 表目錄 表2.1 初始分析尺寸 26 表2.2 PZT-5H材料特性表 26 表2.3 基材之材料常數表 27 表2.4 作用長度於薄膜10 μm 之位移分析 31 表4.1 微結構應用之相關黃光參數 48 表4.2 各結構層相關製程參數 48 表5.1 荷重計校正參數值 65 表5.2 單層與積層 位移-出力數據表 66 符號表：形變量：剪切型壓電特性：作用於壓電材料之驅動電場大小：壓電材料之作動長度：驅動電壓：壓電致動器厚度

REFERENCES

- 參考文獻 [1] R. G. Sweet, "High frequency recording with electrostatically deflected ink-jets," *Rev. Sci. Instrum.* Vol. 36, pp. 131, 1965.
- [2] R. G. Sweet, "Signal apparatus with fluid drop recorder," U.S. Patent 3596275, 1971.
- [3] W. L. Buehner, J. D. Hill, T. H. Williams, and J. W. Woods, "Application of ink-jet technology to a word processing output printer," *IBM J. Res. Dev.* Vol. 21, 1968-1977.
- [4] H. P. Le, "Progress and Trends in Ink-jet Printing Technology," *J. imaging sci. technol.*, Vol. 42, pp. 49-62, 1998.
- [5] C. W. Hansell, "Measuring Instrument of Recording Type," U.S. Patent 2512743, 1950.
- [6] Bartky, et al., "Multi-channel array pulsed droplet deposition apparatus," U.S. Patent 4992808, 1991.
- [7] Vincent Ferrer, "Operational properties of Piezoelectric Shear-Mode Actuator," Condensed Matter Physics Department of Microelectronics and Information Technology.
- [8] Yong Zhou, "Applications of Page Wide Piezo Inkjet Printing to Commercial and Industrial Market," Spectra Inc., www.spectra-inc.com [9] D. Wallace, H. J. Trost, and U. Eichenlaub, "Multi-fluid Ink-Jet Array for Manufacturing of Chip-Based Microarray Systems," MicroFab Technologies, Inc.
- [10] Kotaro Yoshimura, Mitsuru Kishimoto, Toshiro Suemune, "Inkjet Printing Technology," *OKI Technical Review* Vol. 64, August, 1998.
- [11] J. Brunahl, Alex, and M. Grishin, "Piezoelectric shear mode drop-on-demand inkjet actuator," *Sensor and Actuator A* 101, pp. 371-382, 2002.
- [12] F. C. Lee, "PZT Printing Applications Technologies, New Devices," *Ultrasonic Symposium, IEEE*, pp. 693-697, 1988.
- [13] W.R. Whel, "The Present State of the Art," *Compeuro, 89-3rd Annual European Computer Conference Hamburg, West Germany*, pp. 46-52, May, 1989.
- [14] F.C. Lee et al., "The Application of Drop-on-Demand Ink Jet Technology to Color Printing," *IBM J. Res. Develop.*, Vol. 28, No. 3, pp. 307, May, 1984.
- [15] D. J. Hayes, D.B. Wallace, M.T. Boldman and R.E. Marusak, "Picoliter solder droplet dispensing," *ISHM J. of Microcircuits & Electronic Packaging*, Vol. 16, No.3, pp. 173-180, 1993.
- [16] D.B. Wallace and D.J. Hayes, "Solder Jet Technology Update," *The International Journal of Microcircuits and Electronic Packaging*, Vol. 21, No. 1, 1998.
- [17] D.J. Hayes, D. B. Wallace and W.R. Cox, "MicroJet Printing of Solder and Polymers for Multi-Chip Modules and Chip-Scale Packages," *IMPAS '99*, 1999.
- [18] W. R. Cox, D. J. Hayes, T. Chen, D.W. Ussery, D. L. MacFarlane and E. Wilson, "Fabrication of micro-optics by microjet printing," *SPIE Proceedings*, Vol. 2383, pp. 110-115, 1995.
- [19] W. R. Cox, T. Chen, D. Ussery, D. J. Hayes, J. A. Tatum and D. L. MacFarlane, "Microjetted lenslet tipped fibers," *Optics Communication*, Vol. 123, pp. 492-496, 1996.
- [20] W. R. Cox, T. Chen, D. W. Ussery, D. J. Hayes, R. F. Hoenigman, D. L. MacFarlane and E. Rabinovich, "Microjet printing of anamorphic microlens arrays," *SPIE Pro.*, 2687, pp. 89-98, 1996.
- [21] 方昱仁, "單體單噴孔壓電致動式噴液裝置之設計與製造," 碩士論文, 國立台灣大學機械工程研究所, 2002.
- [22] 朱凱隆, "壓電式噴墨印相頭內外流場特性之量測研究," 碩士論文, 國立清華大學動力機械工程研究所, 2003.
- [23] 洪銘青, "Picojet列印頭之噴墨效能分析," 碩士論文, 私立大葉大學機械工程研究所, 2005.
- [24] 蔡煒銘, "擠壓式壓電噴頭噴墨行為之數值研究," 碩士論文, 私立大葉大學機械工程研究所, 2005.
- [25] 鄭江河, 胡榮章, 葉東昇與林烜鵬, "壓電式噴墨頭及其製作方法," 中華民國, 專利194947, 2004.
- [26] K.Uchino and S. Takahashii, "Multilayer ceramic actuators", *Current Opinion in Solid State & Materials Science*, Vol. 1, pp. 698-705, 1996.

- [27] A. Dogan, Q. C. Xu, K. Onitsuka, S. Yoshikawa, K. Uchino and R. E. Newnham, " High Displacement Ceramic-Metal Composite Actuator, " *Ferroelectrics*, Vol. 156, pp. 1-6, 1994.
- [28] J. F. Fernandez, A. Dogan, J. T. Fielding, K. Uchino and R. E. Newnham, " Tailoring the Performance of Ceramic-Metal Piezocomposite Actuators Cymbals, " *Sensors and actuators A65*, pp. 228-237, 1998.
- [29] W. Zhu et al., " Design and fabrication of a novel piezoelectric multilayer actuator by thick-film screen printing technology, " *Sensors and Actuators A86*, pp. 149-153, 2000.
- [30] 楊實文, " 壓電噴墨頭-微陣列致動器之設計與製作, " 碩士論文, 私立大葉大學機械工程研究所, 2003.
- [31] 顧孝鈞, " 壓電微致動器之製作與量測, " 碩士論文, 私立大葉大學機械工程研究所, 2004.
- [32] 許富強, " 奈米微液滴產生器之壓電致動器模組研究, " 碩士論文, 私立大葉大學機械工程研究所, 2005.
- [33] Y. Xu, " *Ferroelectric Materials and Their Applications*, " North-Holland, New York, Vol. 10, 1991.